

PTO-1449 Information Disclosure Citation in an Application		Application No.	Applicant(s) Dipankar (nmi) Chandra, et al.		
		Docket Number 004578.1148	Group Art Unit	Filing Date	

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11/13/01

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	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
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B	4,809,552	3/7/89	Johnson	73	517	11/23/87
C	4,899,125	26/90	Kurtz	338	2	7/24/87
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EXAMINER <i>[Signature]</i>	DATE CONSIDERED <i>7/29/2003</i>	

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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